

[Name of Document] ABSTRACT

A process system 1 comprises a process apparatus 10 which performs a predetermined process on a wafer W, a plurality of detection means which detect statuses in the process apparatus 10, an abnormality detection section 15 which detects an abnormality in detection information from the plurality of detection means, an alarm generation section 16 which generates an alarm when the abnormality detection section 15 detects an abnormality, an information storage section 17 which stores the detection information from the detection means in the process apparatus 10 and alarm information as a process history of the process apparatus 10, an alarm-related information acquisition section 18 which selectively acquires information relating to an alarm selected from the information storage section 17, and a display section 21 which displays alarm-related information acquired by the alarm-related information acquisition section 18.